

# THIN FILM DEPOSITION



Vacuum Systems Technologies and Services Ltd.

## TFDS - 870

INTEGRATED GLOVE BOX  
EVAPORATOR

NANOTECHNOLOGY  
TODAY TREND



Made in cooperation with MBraun USA, the thin film deposition system is integrated with inert gas glove box.

TFDS - 870 meets the new trend nanotechnology R&D or low scale production requirements.

The vacuum chamber comes with two high grade aluminum doors:

- front sliding door opens into the glove box;
- rear revolving door opens to room ambient atmosphere.

Both doors are secure pneumatically and are locked to prevent contamination of the glove box. The system prevents accidental exposure of the glove box to ambient air.

The rear door chamber has a 4" nominal viewing windows with Pyrex® glass and additional protective glass.





- MBraun inert gas glove boxes integrated
- Variety of deposition sources, including thermal deposition, RF or DC sputtering, E-beam, etc.
- 500x500x500mm vacuum chamber
- Turbomolecular pump or cryogenic pump stacks
- Dry roughing pumping
- Gas inlets with MFC and shutoff valve
- Up to 200mm diameter substrate
- Rate & thickness control
- Substrate heating, cooling, rotation & tilting
- Source & substrate shutters
- Thickness & rate control
- Fully Automatic Control PC/PLC
- Human Machine Interface software
- The automatic recording feature, works as data logger for all analog available data



## Contact



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